**B.Tech III Year I Semester**

**JNTUA COLLEGE OF ENGINEERING (AUTONOMOUS) PULIVENDULA**

**19AME65e- NEMS & MEMS**

*(Open Elective-II)*

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**Course Objectives:** The objectives of the course are to make the students learn about

- Familiarize the basics of MEMS and NEMS
- Focus on the available tools and procedures to analyze and design micro/nano-scale engineering systems
- Demonstrate main issues stemming from operating in micro and nano length scale.
- Train MEMS and NEMS devices and their applications
- Impart fabrication and modeling aspects of MEMS and NEMS devices
- Enable a systematic design approach to engineering projects

**UNIT – I: INTRODUCTION:** **10 Hrs**

New trends in Engineering and Science: Micro and Nano scale systems, Overview of Nano and Micro Electromechanical Systems, Micro electromechanical systems devices and structures, Nanotechnology and (N+1) Problem, Physical and Technological limitation of miniaturization;Nanoscale Structures / Nanoparticles: Adhesion, Nanotubes, Nanowires, Quantum Dots, Multilayered structures, Nanocluster Composites Crystals: Lattices, Nanocrystals and nanoparticles.

**Learning Outcomes:**

At the end of this unit, the student will be able to

- Explain the concepts, nanostructures and nanotechnology. **L2**
- Identify the principles of processing, manufacturing and characterization of nanomaterials and nanoscale systems. **L3**
- Apply electronic microscopy, and nano indentation techniques to characterize nano materials and nanostructures. **L3**

**UNIT – II: MODELING OF MEMS AND NEMS:** **10 Hrs**

Introduction to modeling, analysis and simulation, Scaling laws for length and time and its effect on modeling, Grain size effect on materials properties (mechanical, electrical, magnetic, etc.), basic electro-magnetic with application to MEMS and NEMS, Modeling developments of micro-and nano actuators using electromagnetic fields, Lumped-parameter mathematical models of MEMS, Energy conversion in NEMS and MEMS.

**Learning Outcomes:**

At the end of this unit, the student will be able to

- Explain the operation of micro devices, micro systems and their applications. **L1**
- Model MEMS devices and structures. **L3**
- Develop micro devices, micro systems using the MEMS fabrication process. **L3**

**UNIT – III: MANUFACTURING TECHNIQUES AND PROCESSES:** **10Hrs**

Cleanroom and Fab Procedures, Vacuum: Vacuum Systems, Pumps and Gauges; Materials for MEMS: Silicon, silicon compounds, polymers, metals; Microfabrication Technologies: Beam Machining – Ion-Beam, E-Beam and LASER processing techniques; Lithographic Patterning – Bulk μMachining, Surface μMachining, SU-8 Lithography & Surface forming, LIGA Process: X-Ray Lithography &UV LIGA; Precision Machining – Precision Milling and turning, μEDM, Micromolding & Embossing, Precision Bonding, Thin Films: Processes, Evaporation, Dry and Wet Etching, Sputtering Deposition; Characterization: Optical Techniques/Microscope, SEM, Optical and Electrical, Properties, Auger and Thin Film Analysis, AFM.

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**Learning Outcomes:**

At the end of this unit, the student will be able to

- Outline computer-aided design, fabrication, analysis and characterization of nano-structured materials, micro- and nano-scale devices. **L2**
- Develop micro/nanosystems for photonics and optical applications. **L2**
- Explain manufacturing processes based on diffusion, deposition and patterning of surfaces. **L4**

**UNIT – IV: MICRO SENSORS AND MICRO ACTUATORS: 8 Hrs**

MEMS Sensors: Piezoresistive pressure sensor, Acoustic wave sensors, Resonant Microsensor, Peizoelectric Rate gyroscope, Capacitive Accelerometer; etc. Nanosensors & Nano biosensors; Design of Actuators: Actuation using thermal forces, Actuation using shape memory Alloys, Actuation using piezoelectric crystals, Actuation using Electrostatic forces (Parallel plate, Torsion bar, Comb drive actuators), Micromechanical Motors and pumps; Nanomotor, Molecular Motor, etc.

**Learning Outcomes:**

At the end of this unit, the student will be able to

- Outline basic approaches for various actuator design. **L2**
- Distinguish between various MEMS sensors. **L4**
- Explain the operation principles of advanced micro- and nanosystems. **L4**

**UNIT – V: CONTROL OF MICROELECTROMECHANICAL SYSTEMS 10 Hrs**

Introduction to Microelectromechanical Systems Control, Control of Microelectromechanical Systems, Intelligent Control of MEMS; Synthesis, Analysis, Fabrication, and Computer-Aided Design of MEMS, Case studies: Design and Fabrication Analysis of Translational Microtransducers, Single-Phase and three phase Reluctance Micromotors, Modeling, Analysis, and Control of Micromirror Actuators; Application of Nanomotor in Bio-medical applications, Nano robots, Electronics based on CNT - Molecular Electronics.

**Learning Outcomes:**

At the end of this unit, the student will be able to

- Identify micro electro mechanical system control for a given application. **L3**
- Synthesis intelligent control of MEMS/NEMS. **L4**
- Evaluate MEMS/NEMS for various applications. **L4**

**Text Books:**

1. Marc Madou, Fundamentals of Micro fabrication, CRC press 1997.
2. Stephen D. Senturia, Micro system Design, Kluwer Academic Publishers,2001
3. J. A. Pelesko and D. H. Bernstein, Modeling of MEMS and NEMS, Chapman & Hall/CRC, 2003.
4. Sergey Edward Lyshevski, Lyshevski Edward Lyshevski, MEMS and NEMS: Systems, Devices and Structures, CRC Press, 2005.

**Reference Books:**

1. Tai Ran Hsu, MEMS and Microsystems Design and Manufacture, Tata Mcraw Hill, 2002.
2. Chang Liu, Foundations of MEMS, Pearson education India limited, 2006
3. Mahalik N P, MEMS, Tata McGraw-Hill Education, 2008.
4. Gianfranco Cerofolini, Nanoscience and Technology: Nanoscale Devices, Springer, 2009.

**Course Outcomes:**

At the end of this Course the student will be able to

- Identify processing and characterization of nanomaterials. **L3**
- Plan operation of micro devices, micro systems and their applications. **L3**
- Describe the implementation of MEMS into products. **L4**
- Explain the operation principles of advanced micro- and nanosystems. **L4**
- Apprise the technology implemented in advanced micro- and nanosystem. **L5**
- Design the micro devices, micro systems using the MEMS fabrication process. **L5**



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